Sample Preparation and Deposition UHV System Model LEED-MBE250



- LEED (Low Energy Electron Diffraction)

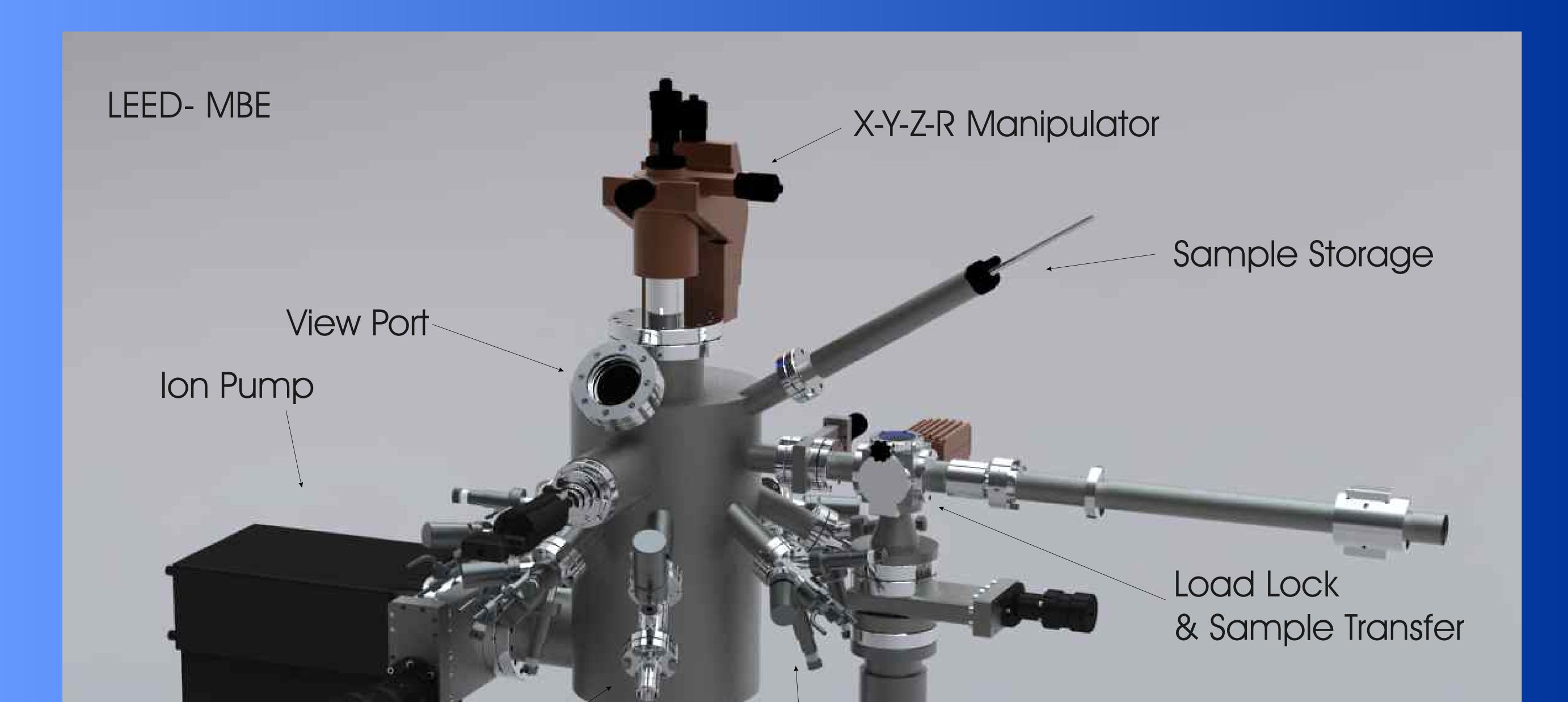
-(AES) Auger Electron Spectroscopy

- Ion Sputter Sample Cleaning

- Thermal Sample Annealing

- (TDS) Thermal Desorption Mass Spectroscopy

- 7 Deposition Sources



Ion Sputter Gun

Deposition Sources (x 7) Positioned Around The Chamber

LEED-AES

FEATURES:

- Continues LEED structure monitoring during film growth from multiply sources

- Load-lock with transfer arm and sample storage

- Sample transfer compatibility with another systems: XPS, SPM and SEM



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